



Tariffs

For external customers and internal customers with commercial financing

Equipment rental cost per 1 hour

No p/p	Equipment	Access type	Price ² , RUB without VAT
1	Transmission electron microscope with probecorrector Titan Themis Z	per hour with AICF operator	17 851
2	Scanning electron microscope with low-vacuum mode Quattro S SEM	per hour with AICF operator	6 933
		per hour without AICF operator ¹	4 633
		per day of training course	70 104
3	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM	per hour with AICF operator	13 548
4	Dual beam scanning electron microscope Tescan Solaris	per hour with AICF operator	13 548
5	Pump probe transient absorption/reflection spectroscopy setup	per hour with AICF operator	4 945
6	Time-Correlated single photon spectroscopy setup	per hour with AICF operator	3 795
7	Femtosecond double pulse microcavity dispersion imaging optical setup	per hour with AICF operator	9 545
8	Compact low-temperature electro-optical imaging setup	per hour with AICF operator	4 370
9	Sample preparation equipment	per hour with AICF operator	2 645

Typical services provided by AICF

No p/p	Typical services	Used equipment	Unit of measurement, sample	Price ³ , RUB without VAT
1	Particle morphology investigation	Scanning electron microscope with low-vacuum mode Quattro S SEM	1 sample	9 233
2	Surface morphology investigation of the sample, if	Scanning electron	1 sample	12 699

	necessary, the use of a backscattered electron detector	microscope with low-vacuum mode Quattro S SEM		
3	Investigation of the elemental composition of the sample (by 5 points)	Scanning electron microscope with low-vacuum mode Quattro S SEM	1 sample	9 233
4	Investigation of the elemental composition of the sample (mapping of 3 areas)	Scanning electron microscope with low-vacuum mode Quattro S SEM	1 sample	16 166
5	Particle morphology investigation	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	15 963
6	Surface morphology investigation of the sample, if necessary, the use of a backscattered electron detector	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	22 621
7	Investigation of the elemental composition of the sample (by 5 points)	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	24 921
8	Investigation of the elemental composition of the sample (mapping of 3 areas)	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	45 244
9	Investigation of the isotopic composition of the sample (mapping of 3 areas)	Dual beam scanning electron microscope Tescan Solaris	1 sample	40 644
10	Preparation and visualization of cross-section	Dual beam scanning electron	1 sample	24 921

		microscope Helios G4 UXe PFIB/SEM/Tescan Solaris		
11	Preparation of lamella for TEM investigation	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	60 966
12	Preparation of lamella for TEM investigation at the given point in accordance with Customer request	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	74 514
13	Investigation of multilayer structures in the STEM mode, including investigation of the elemental composition of the sample (along the line)	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	45 244
14	Investigation of the crystallographic orientation of the grain structure (EBSD)	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM/Tescan Solaris	1 sample	Договорная, зависит от ТЗ
15	Investigation of the morphology of nanoparticles in TEM or STEM modes	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	22 451
16	Investigation of the grain structure of a sample including determination of dislocation density	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	44 902
17	Investigation of the crystal structure of a sample using electron diffraction	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	67 354
18	Visualization of the crystal structure of the sample in	Transmission	1 sample	44 902

	high resolution TEM or STEM	electron microscope with probecorrector Titan Themis Z		
19	Solution of the crystal structure of a sample using electron diffraction tomography	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	177 311
20	Investigation of the elemental composition of the sample using energy dispersive X-ray spectroscopy (EDX) (mapping of 3 areas)	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	40 302
21	Mapping of the elemental composition of the sample using energy dispersive x-ray spectroscopy (EDX) with atomic resolution (mapping of 3 areas)	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	58 154
22	Investigation of the elemental composition of the sample, including light elements, using electron energy loss spectroscopy (EELS) (spectra acquisition at 5 points)	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	44 902
23	Mapping of the elemental composition of the sample, including light elements, using electron energy loss spectroscopy (EELS) in the STEM mode (mapping of 3 areas)	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	62 754
24	Visualization of nanoparticles using electron tomography	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	177 311
25	Visualization of multilayer structures (heterostructures) with atomic resolution	Transmission electron microscope with probecorrector Titan Themis Z	1 sample	62 754
25	IR spectrum measurement spectra acquisition at 5 points	IR microscope Bruker Lumos	1 sample	6 785

For internal customers⁴

№	Equipment	Access type	Price, RUB
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p/p			without VAT
1	Transmission electron microscope with probecorrector Titan Themis Z	per hour with AICF operator	4 718
		per hour without AICF operator ¹	3 568
2	Scanning electron microscope with low-vacuum mode Quattro S SEM	per hour with AICF operator	1 836
		per hour without AICF operator ¹	686
		per day of training course	5 493
3	Dual beam scanning electron microscope Helios G4 UXe PFIB/SEM	per hour with AICF operator	3 416
		per hour without AICF operator ¹	2 266
		per day of training course	27 328
4	Dual beam scanning electron microscope Tescan Solaris	per hour with AICF operator	3 416
		per hour without AICF operator ¹	2 266
		per day of training course	27 328
5	Pump probe transient absorption/reflection spectroscopy setup	per hour with AICF operator	2 645
6	Time-Correlated single photon spectroscopy setup	per hour with AICF operator	1 495
7	Femtosecond double pulse microcavity dispersion imaging optical setup	per hour with AICF operator	7 245
8	Compact low-temperature electro-optical imaging setup	per hour with AICF operator	2 070
9	IR microscope Bruker Lumos	per hour with AICF operator	1 836
10	Sample preparation equipment	per hour with AICF operator / without AICF operator	645

Prices are indicated for equipment rent only; interpretation of results and preparation of reports are charged separately.

Duration and contents of the training are determined based on the trainee's level.

¹ Access granted only after completing a corresponding training course

² The cost is indicated without taking into account the sample preparation

³ Internal customers with external (commercial financing), as well as participants of the Skolkovo project, are provided with an additional discount of 20% of the specified tariff. Services rendered with the help of Titan Themis Z equipment to the Skolkovo project participants are calculated at an individual rate (upon request)

⁴ Including research projects of Skoltech employees, which are funded from a grant from the Skolkovo Foundation, grants from the Russian Science Foundation, RFBR, Ministry of Education and Science, Skoltech startups. The tariff is applied subject to the provision of supporting documents, otherwise the tariff "For external clients and internal clients with commercial financing" is applied